

Resource Summary Report

Generated by [RRID](#) on Aug 6, 2026

Rigaku: TXRF310Fab

RRID:SCR_020481

Type: Tool

Proper Citation

Rigaku: TXRF310Fab (RRID:SCR_020481)

Resource Information

URL: <https://www.rigaku.com/products/semi/txrf310>

Proper Citation: Rigaku: TXRF310Fab (RRID:SCR_020481)

Description: Wafer surface contamination metrology by TXRF with measurement of trace elemental surface contamination.

Resource Type: instrument resource

Keywords: Rigaku, Semiconductor Metrology, Instrument Equipment, USEDit,

Availability: Commercially available

Resource Name: Rigaku: TXRF310Fab

Resource ID: SCR_020481

Alternate IDs: Model_Number_TXRF310 Fab

Record Creation Time: 20220129T080350+0000

Record Last Update: 20260801T190658+0000

Ratings and Alerts

No rating or validation information has been found for Rigaku: TXRF310Fab.

No alerts have been found for Rigaku: TXRF310Fab.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.